



Nanostructures for Photocatalysis

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Message from the Guest Editor

This Special Issue, “Nanostructures for Photocatalysis”, aims at contributing to assess the state-of-the-art of breakthroughs in novel photocatalytic materials, brought about from the continuing progress of advanced nanoscience and nanotechnology in recent years. Specifically, nanostructured-controlled photocatalysts are the subject of this issue. Therefore, with respect to usual semiconductor materials, mostly titania-based, new materials, such as metal oxides, metal organic framework, metal complexes, and porous materials add to the list of candidates for photocatalytic applications, profiting from potential high performance related to their specific nanostructures.





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Message from the Editor-in-Chief

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